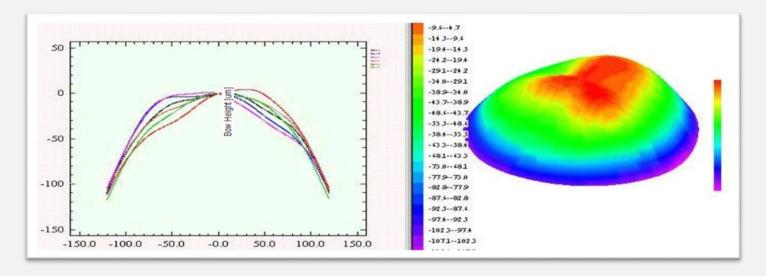
FSM 128 Film Stress & Wafer Bow Measurement System



Non-contact Laser scanning

Room
Temperature
Wafer Size: 50mm to
300mm
Manual Loading

Semiconductor, Optoelectronics & FPD Application





Frontier Semiconductor

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FSM 128 Film Stress & Wafer Bow Measurement System

Introduction

The FSM 128 is an advanced system for precise wafer stress, curvature, and bow measurement. Utilizing a non-contact technique, it ensures accuracy and reliability. Available in Film Stress & Wafer Bow Measurement System, it supports wafers up to 300mm, providing 2D/3D stress mapping with intuitive operation.

Specifications

- Film Stress Range: 1 MPa to 1.4 GPa (for Si wafers with ≥1µm bow/curvature change)
- **Bow Sensitivity:** Detects 1-micron height changes (P-doped Si)
- Wafer thickness: <5mm
- Scan Range: 3mm edge exclusion
- Mapping: 32 scan lines (6 recommended) with 40 data points/mm
- **Bow Measurement:** Measures bow heights up to 2000μm
- Advanced Optics: Patented dual laser switching for accuracy
- **Software:** Windows 7–11 compatibility, data export to ExcelTM, JPEG maps
- Operating Conditions: Ambient temperature
- Measurement Method: Non-contact laser scanning
- Wafer Compatibility:
 - o **FSM 128NT:** 50mm to 200mm
 - o **FSM 128L:** 50mm to 300mm
- **Scanning:** High-precision single scan and programmable multiple diametric scans for 2D/3D mapping
- Repeatability: 1% (1 sigma) on a 20m curvature mirror standard
- Accuracy: <2.5% on a 20m radius curvature mirror
- Laser Class: Class 1

Data and Connectivity

• Export results to ExcelTM or JPEG.

System Requirements

• Computer: Intel Core i5 or later, 2GB RAM, 1TB hard drive, 4 USB ports, 2 Ethernet ports.

Dimensions & Weight

- **FSM 128NT**: 14" (W) x 20" (D) x 16" (H), 55 lbs
- FSM 128L: 14" (W) x 28" (D) x 16" (H), 60 lbs

Power Requirements

• 110V/220V; 20A

Notes

- Wafer bow is the deviation of the center point of the wafer's front surface when supported on a 3-point system.
- Repeatability and accuracy depend on film type, thickness, and substrate.



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